

U.S. Department of Commerce, Patent and Trademark Office

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use several sheets if necessary)

Sheet 1 of 1

Application No.:	09/578,798
Filing Date:	May 23, 2000
First Named Inventor:	Jaime Puris
Group Art Unit:	2873
Examiner Name:	William C. Choi
Confirmation No.:	5190
Attorney Docket No.:	NAN040 US

U.S. Patent Requirements

U.S. Patent Documents						
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
W. C.	5,348,002	9/20/94	Caro	128	633	
W. C.	5,555,471	Sep/10/96	Xu et al	356	357	
W. C.	5,914,782	Jun/22/99	Sugiyama	356	351	
W. C.	6,392,752	5/21/02	Johnson	356	511	

OTHER ART (Includes Author, Title, Date, Pertinent Pages, Etc.)

C. C.		Other - GCR (including Author, Title, Date, Published Pages, etc.)
7		Stue, B et al., "Rapid Characterization and Modeling of Pattern-Dependent Variation in Chemical-Mechanical Polishing", IEEE Transactions on Semiconductor Manufacturing, Vol. 11, No. 1, pp. 129-140 (Feb. 1998)

Exemples

200

Date Considered

10/3/03

*EXAMINER Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

Sheet 1 of 1

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U.S. Patent Documents							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
W.C.	8. 4,512,661	Apr. 23, 1985	Claus et al.	356	351		
W.C.	9. 5,604,591	Feb. 18, 1997	Kitagawa	356	351		
W.C.	10. 6,568,290	May 27, 2003	Paris	73	866		
Foreign Patent Documents							
	Document	Date	Country	Class	Subclass	Translation	
						Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
W.C.	11. Malacara, Daniel et al. "Interferogram Analysis For Optical Testing" 1998, Marcel Dekker, Inc. pp. 113						
Examiner <u>W.C.</u>		Date Considered <u>8/22/03</u>					
*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							